## Pressure measurements

ELEC-E5710 Sensors and Measurement
Methods

## Pressure

- Compressed gas or liquid aims to expand, this is called pressure.
- Defined as a ratio of force and surface area

$$
p=\frac{F}{A}
$$

- SI unit for pressure is Pascal,
- $\mathrm{Pa}=\mathrm{N} / \mathrm{m}^{2}=\mathrm{kg} / \mathrm{m} / \mathrm{s}^{2}$
- After temperature, pressure is the second most measured process quantity.


## Units of pressure

|  | Pa | bar | psi | at | atm | Torr | $\mathbf{m m H g}$ | inHg | $\mathrm{cmH}_{2} \mathrm{O}$ |
| :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: | :---: |
| 1 Pa | 1 | $10^{-5}$ | 1.45-10-4 | $1.02 \cdot 10^{-5}$ | 9.87-10-6 | 7.5•10-3 | 7.5-10-3 | 2.96-10-4 | 0.0102 |
| 1 bar | $10^{5}$ | 1 | 14.5 | 1.02 | 0.987 | 750 | 750 | 29.6 | 1020 |
| 1 psi | 6890 | 689 | 1 | 0.070 | 0.068 | 51.7 | 51.7 | 2.04 | 70.3 |
| 1 at | $9.81 \cdot 10^{4}$ | 0.981 | 14.2 | 1 | 0.968 | 736 | 736 | 29 | 1000 |
| 1 atm | 101325 | 1.01 | 14.7 | 1.03 | 1 | 760 | 760 | 30 | 1030 |
| 1 Torr | 133 | $1.33 \cdot 10^{-3}$ | 0.0193 | $1.36 \cdot 10^{-3}$ | $1.32 \cdot 10^{-3}$ | 1 | $\sim 1$ | 0.0395 | 1.36 |
| 1 mmHg | 133 | $1.33 \cdot 10^{-3}$ | 0.0193 | $1.36 \cdot 10^{-3}$ | $1.32 \cdot 10^{-3}$ | $\sim 1$ | 1 | 0.0395 | 1.36 |
| 1 inHg | 3380 | 338 | 0.49 | 0.0344 | 0.033 | 25.3 | 25.3 | 1 | 34.4 |
| $1 \mathrm{cmH}_{2} \mathrm{O}$ | 98.1 | $9.81 \cdot 10^{-4}$ | 0.0142 | 0.001 | $9.68 \cdot 10^{-4}$ | 0.736 | 0.736 | 0.029 | 1 |

## Types of pressure

- Absolute pressure
- Compared to vacuum, so pressure is always greater than zero
- Meters for small absolute pressure are called vacuum gauges
- Current air pressure
- Depends on circumstances, altitude etc.
- Gauges are called barometers, absolute measurement
- Overpressure and underpressure
- Reference pressure is the current air pressure
- Pressure difference measurement
- Reference value is something else than vacuum or current air pressure Pressure difference



## Static and dynamic pressure

- Static pressure: static pressure is measured when the fluid is at rest
$p$
- Dynamic pressure: caused by directional kinetic energy of matter

$$
\frac{1}{2} \rho v^{2}
$$

- Total pressure = static pressure + dynamic pressure


## Hydrostatic pressure

- Pressure caused by the gravitational force of the liquid or gas:

$$
p=\rho g \Delta h
$$

$\rho=$ fluid density $; \mathrm{g}=$ gravitational acceleration; $\mathrm{h}=$ depth of fluid

## Measuring instruments

- Calibrating instruments are based on the definition of pressure
- Dead weight testers
- Manometers
- Field measuring instruments
- Transitional and force sensors

- For special applications e.g. thermic and ionization measuring instruments


## Dead weight tester

- Typical calibrating device for meters
- Transforms the mass of weights to liquid or gas pressure with the help of a cylinder and a piston
- High accuracy is obtained by dimensional measurements (the diameter of the piston)


Schematic diagram: Dead Weight Tester

## Dead weight tester

- Air or nitrogen as a medium when the pressure is low ( $1 \mathrm{kPa}-5 \mathrm{MPa}$ ) and oil or water with higher pressure (5 $\mathrm{MPa}-2,5 \mathrm{GPa}$ )
- Problems
- Small pressure: friction
- High pressure: elastic deformation of the cylinder-piston combination
- Important during calibration
- Determination of the effective area of the cylinder piston
- Determination of the mass of the weights


## Manometer


a)


b)

a) U-tube manometer,
b) Well type manometer,
c) Inclined tube manometer,
d) Micro manometer
e) Barometer

## Manometer

- Filled with water, mercury or e.g. butyl alcohol
- Pressure difference $p_{1}-p_{2}$ can be calculated from the altitude difference of the columns

$$
\begin{aligned}
& p_{1}-p_{2}=\rho g h, A_{2}=A_{1} \\
& p_{1}-p_{2}=\rho g h\left(1+\frac{A_{2}}{A_{1}}\right), A_{2} \neq A_{1}
\end{aligned}
$$

## Manometer (example)

- U-shaped resistive wire in mercury which short circuit the wire
- Measuring with a bridge connection
- Equilibrium when the pressure difference of the tube is zero
- When the other side is exposed to pressure, the bridge connection is not in equilibrium and there is an output signal
- When the pressure increases on the left side, the resistance also increases. On the other side, the resistance decreases
- The output voltage is proportional to the
 resistance difference


## Manometer (example)

- Pros:
- Simple and reliable instrument to measure gas pressure
- Inexpensive
- Cons:
- Low time constant
- Sensitivity to vibrations
- Large
- Mercury contaminates the gas


## Mechanical pressure sensors (no fluid) <br> - transition pressure sensors

(a) Flat film
(b) Waved film
(c) Capsule
(d) Bellows
(e) Straight tube
(f) C-shaped bourdon tube
(g) Bent bourdon tube
(h) Twisted bourdon tube
(i) Spiral bourdon tube

| (a) | (b) | (c) |
| :---: | :---: | :---: |
| (d) | (e) | (f) |
| (g) | Motion <br> (h) | (i) |

## Bourdon tube

- Flat tube made of brass or steel
- Functioning based on springback factor
- Inexpensive, reasonable overall accuracy in pressure gauges
- Absolute pressure up to 6 MPa and overpressure up to 700 MPa



## Flexible film

- Sensitivity can be enhanced by corrugating the film
- Releases tension in the film
- Enhanced sensitivity and linearity

(B)



## Piezoresistive pressure sensor

- The most common type,
- To all applications
- Typically a semiconductor stretch slip attached to a flexible film
- Measurement with a Wheatstone bridge


## Temperature dependency of a piezo pressure sensor

- The temperature coefficient of a piezo sensor's sensitivity is negative and rather big
- Temperature compensation is required
- Often with bridge connections



## Strain gauge pressure sensor

- Electrical resistance of a strain gauge changes when material deforms.
- When a material comes longer and narrower, its resistance changes.



## Capacitive pressure sensor

- Other electrode (e.g. silicon) functions a pressuredisplacement transformer while the other one is fixed
- As pressure increases the distance between the electrodes decreases

- Capacitance increases
- In differential version, the capacitance of the other one increases and the other one's decreases
- Linearity and stability are good but the measuring electronics is more complicated


## Capacitive pressure sensor in practice

- 2 insulator films made of special metal compound
- Also to measure corrosive materials
- Pressure difference to sensor film via oil
- Desired permittivity to capacitor
- Absorbs shocks and vibrations



## Piezo sensor vs. capacitive sensor

- Films can be protected against overpressure with a mechanical support
- Movement of a capacitive film is bigger than in piezo sensors (better support is possible)
- In film based sensors, meter breaks down at pressures 10 times (piezo) and 1000 times (capacitive) higher than the upper limit of the measurement range
- Flatness of the film is important for capacitive sensors
- Displacements are often smaller that thicknesses
- Capacitive sensors have better relative sensitivity
- Stray capacitance can easily be as big as nominal capacitances (Measuring circuits must be close to sensors!)
- Both have low hysteresis


## Inductive (reluctance) pressure sensor

- Change in pressure bends magnetic film
- Air gap between the iron core and the film changes and, thus, the reluctance also changes
- Inductance of the coil changes
- Measurements with small displacements (<30 mm)
$\rightarrow$ Small pressures



## Reluctance sensor

Material $i$ causes a reluctance $R_{i}=\frac{l_{i}}{\mu_{i} A_{i}}$
$l_{i}=$ distance experienced by flux in material
$\mu_{i}=$ permeability of the material
$A_{i}=$ area in material which is perpendicular to direction of propagation


Inductance of a coil, which contains $N$ turns $L=\frac{N^{2}}{\sum_{i=0}^{M} R_{i}}$

## Pros of reluctance sensor

- Low temperature dependency
- Very small pressure difference measurements
- Due to small pressure cavity, there is good endurance to overpressure ('short circuit' of the magnetic parts does not disturb)
- In practice, it almost never breaks down


## Inductive pressure sensor, Linear Variable Differential Transformer (LVDT)

- Moving iron core changes the transformer ratio



## Piezoelectric pressure sensor

- Electric charge of the crystal surfaces change when the surface is strained
- Leakage currents compensate the charges on the crystal surfaces
- Not suitable to measure static pressure



## Piezoelectric pressure sensor

- Pros
- High output signal and specific frequency
- Small size, durable
- Cons
- High output impedance and temperature sensitivity
- Requires an amplifier
- Only dynamic measurement


## Cantilever Pressure sensor



